



Imaging, Vision and Pattern Recognition

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Deadline for manuscript
submissions:

closed (20 May 2024)

Message from the Guest Editor

Dear Colleagues,

With the advent of Deep Learning techniques, there have been massive developments in Computer Vision and related fields that outpace our publishing capability. These new models and approaches are still in preprint; a few research groups have presented the novel applications, refinements and extensions. This overwhelming research pace makes it difficult to distinguish between the foundational papers, methodological work and simple case studies.

In this Special Issue, we focus on methodological work and invite submissions exploring cutting-edge Computer Vision and Pattern Recognition Applied Research that is generalizable and has the potential to go beyond case studies or new method applications. We are interested in application strategies. Do you think your solution represents a refinement of a particular method or a solution strategy beyond your particular area?

We wish to receive papers that present concrete, real-world results from Computer Vision approaches used to solve problems, and also investigate and discuss their broader application. The authors are encouraged to submit relevant research articles or review articles on the above-mentioned topics.





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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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